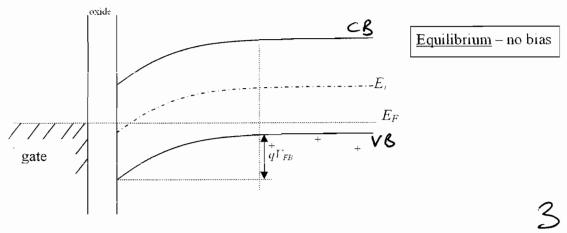
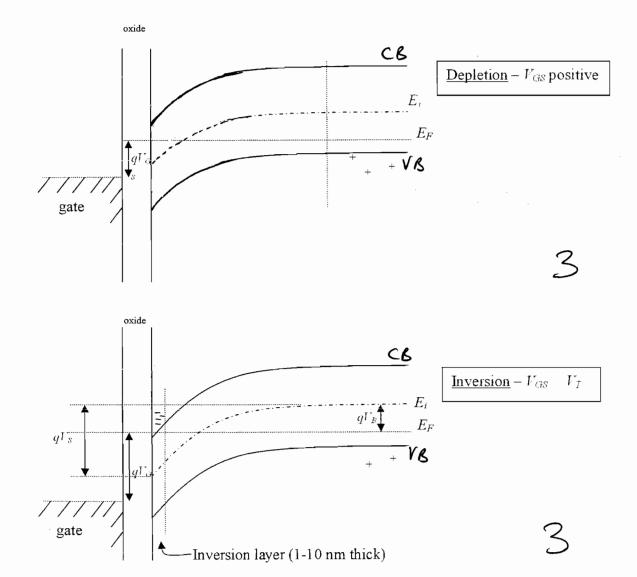
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Q1 (b)





QI (cont.) (b) Main variation in VT is through NA Z term. Cox increases as the oxide thickness reduces due to scaling. Na must mèrease to reduce depletion regions in line with scaling. Overall. Nat/Cox reduces which reduces VT. Both VFB and VB are only weakly dependent on NA and therefore do not influence V7. 4 VT needs to be reduced during scaling to minimise power dissipation during switching As the third term in V7 expression is 2 reduced due to scaling the other terms start to dominate and hence V7 reduces wery little.

Change in threshold reltage due to exide though $\Delta V_7 = \frac{Q_{SS}}{C_{ox}} = \frac{5 \times 10^{-7}}{E/d_{ox}}$ $= \frac{5 \times 10^{-7} \times 5 \times 10^{-8}}{3.45 \times 10^{-13}}$

= 0.072V

3

Q2 a) When electrons goin sufficient energy form on electric field they can create e-h pairs by tous firming their kinetic energy to break a crystal bond. Secondary electrons break a crystal bond. Secondary electrons and holes so created are accelerated in turn to produce more e-h. pairs.

produce more e-h. pairs

2è = 2è = 2è
1h+
2 = 1h+

This process is important for small devices since very high fields are encountered.

(b) $\frac{dE}{dx} = \left| \frac{en}{e} \right| \approx 0$ $\frac{en}{e} = 0$

Assumptions from question $x = \beta$ and = const. $1 - \frac{1}{M_n} = \int x dx = xW$

: . XW = 1 for breakdown (i.e. Mn > 0) 2

i.e. $3.8 \times 10^{7} \exp\left(\frac{-3 \times 10^{6}}{E_{n}}\right) \times 0.05 \times 10^{-6} = 1$

 $\frac{3\times10^6}{\text{En}} = \ln\left[3.8\times10^7\times0.05\times10^{-6}\right]$

 $= \frac{3\times10^6}{\ln[3.8\times10^7\times0.05\times10^{-6}]} = 4.67\times10^6$

Q2 (cont.)

Now AE = endx

(from Poisson's Equation)

 $= \frac{1.6 \times 10^{-19} \times 3 \times 10^{21} \times 0.05 \times 10^{-6}}{1.17 \times 10^{-10}}$

= 2.05 × 10 V/m 2

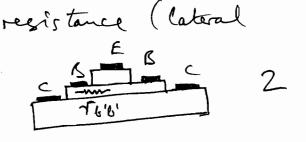
Breakdown voltage = avea under E(se) diagram $= E_{n} \times 0.05 \times 10^{-6} + \left(E_{n} - \frac{\Delta E}{2}\right) \times 1 \times 10^{-6}$

= 0.2 + 3.65 = 3.85V

frequency - take electron velocity 1×10 ms-1

= 100 GHZ

(a) Tbb' = base access resistance between base contact and centre of the emitter)



= in put dynamic $I_{\pi} = \frac{\partial \overline{I}_{\varepsilon}}{\partial V_{s\varepsilon}} = \frac{kT}{gI_{\varepsilon}}$ resistance of EB

50 = output conductance (DIC)

- due to Early Effect

In an HBT structure:

high doping in the base is possible without reducing the gain.

To is in creased since depletion of the base (Early effect) greatly reduced due !
to high doping there.

Fa is maffected.

France is increased due to reduced Tob'
hereased to results in a more linear amplification

Q3 (cont.)

(b) TBE - delay in charging CBE capacitance through in triusic diode (smitter-base) resistance.

 $T_{BE} = \frac{dQ_{BE}}{dI_{E}} = C_{BE} \frac{dV_{BE}}{\partial I_{E}} = \frac{kT}{gI_{E}}.C_{BE}$

To - base travit delay - time for electrons to diffuse through the base.

equivalent capacitance $C_B = \frac{\partial Q_B}{\partial V_{BE}}$ where Q_B is the excess base charge.

CBC - delay in charging CBC through the intrinsic amilter-base diode resistance in trinsic amilter and collector resistance schee pluse amilter and collector resistance schee current must also flow through these resistors ie. CBC = (kT + re + rc) CBC.

Cc - collector transit time - some argument
as Ts i.e. equivalent rapacitance
= $\frac{\partial Q_c}{\partial V_{SE}}$ Qc - charge in transit 2
in collector

Since of of this charge is driven by VRE, the total delay can be represented by Co'e shich includes the sum of all the capacitans delays above.

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2

4 (a) transconductance
$$g_{m} = \frac{\partial I_{0}}{\partial V_{as}}$$
 (definition)

$$=1$$
 at $f=f_7$

$$\Rightarrow f_{\tau} = \frac{g_{m}}{2\pi C_{6x} Z L} = \frac{Z_{m} C_{6x}}{2\pi G_{6x} Z L} (V_{4s} - V_{\tau})$$

$$=\frac{\mu}{2\pi L^2}\left(V_{4s}-V_{7}\right)$$

These expression; assume that the velocity of the electrons will continue to rise as $N = \mu E$ but in fact the velocity saturates at high fields then got lengths are short, hence got and for will not rise as fast as predicted above as h shrinks.

Reductions in Is and gon due to velocity saturation can be compensated by in oraning Cox. Also the threshold voltage can be reduced as Cox increases since the former will in crease as the chunnel doping increases during the shrinking of process.

(b) Transit-time
$$f_7 = 2\pi T$$
 $7 = \frac{v}{L}$

Transit-time $f_7 = 2\pi T$ $7 = \frac{v}{L}$

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Transit-time $f_7 = 2\pi T$ $7 = \frac{v}{L}$

Transit-time $f_7 = 2\pi T$

Transit-time

= 6x105Vm-1 = 6kV/cm

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(3)

4(cmt.) relocity $v = 1 \times 10^{5} \left(\frac{6}{7+6}\right) \text{ ms}^{-1} = 0.46 \times 10^{5} \text{ ms}^{-1}$ $= \frac{v}{2\pi \times 5 \times 10^{-6}}$ $= 146 \text{ GHz}. \text{ } = \frac{0.46 \times 10^{5}}{2 \times 5 \times 10^{-6}}$

 $E = \frac{3}{1\times10^{-7}} = 300 \text{ kV/cm}$ $N = 1.8 \times \frac{300}{307} = 0.977\times10^{5} \text{ ms}^{-1}$

from the succession of the section given for reasoned arguments showing knowledge of the issues (2 only required).

May include:

2.0.977×10⁵

2.77×10⁵

2.77×

- · Cost of setting up proces equipment and
- · gutolerable S-D leakage wouts for L < 9nm
- · Inability to develop "high-k" dielectrics of sufficient quality and reliability.
- · Control of small dimensions to required tolerances becomes impossible.
- · Non-available high conductivity interconnect metal and "low-k" dichetties.
- · Accurate high frequency device and arount wooleds
- · Font-and processing worlds not available